

Precision Measurement of Mechanical Loss & Thermal Noise Characterisation

E-TEST: Einstein Telescope EMR Site

Hemendra Singh
Precision Mechatronics Laboratory - ULiege
<https://www.pml.uliege.be>

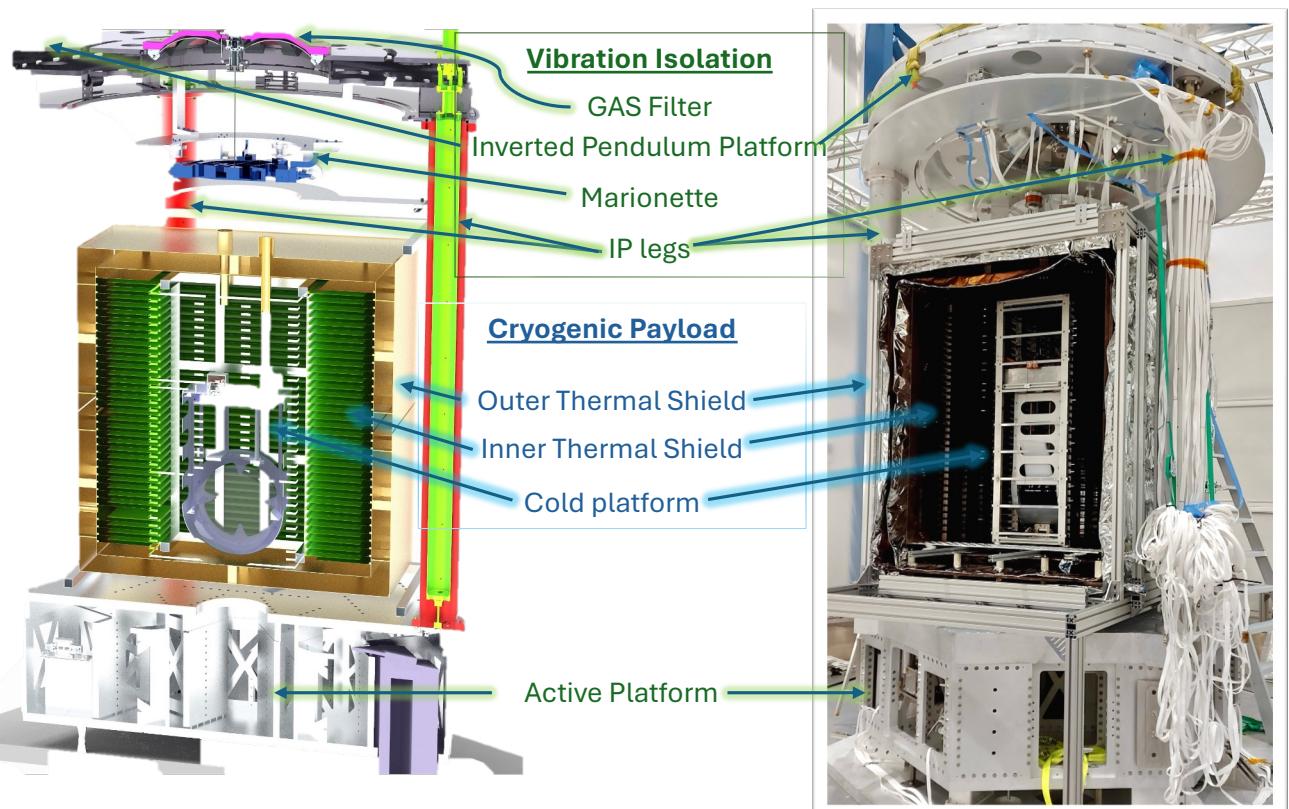


E-TEST Cryogenic Prototype

From Concept, through Design, to Creation!!

The E-TEST project, supported by Interreg EMR and ET2SME, uses CSL's existing infrastructure to build the facility.

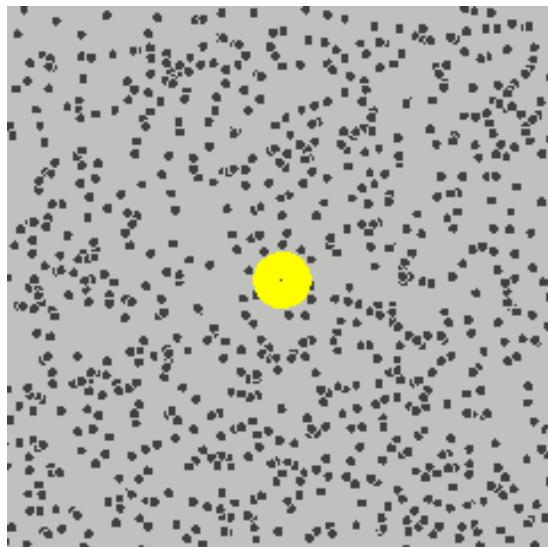
- Isolated at low frequency (0.01-10 Hz)
- Radiative cooling (20 K)
- Large Si mirror (~100 Kg)



Overview: Thermal Noise

Fluctuation-Dissipation Theorem

Relates noise spectrum + system's linear responses to applied perturbations:



Brownian motion of a particle

Power spectrum
of noise

$$x^2(\omega) = \frac{4k_B T k \phi(\omega)}{\omega[(k - m\omega^2)^2 + k^2\phi^2]}$$

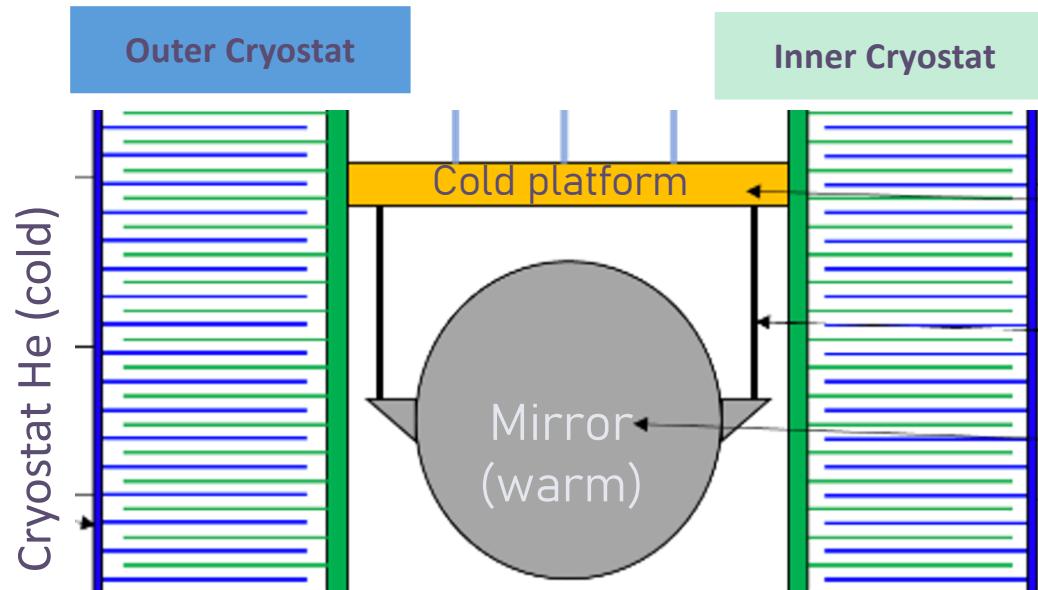
- This equation depends on one unknown, ϕ , the loss angle.
- **Quality Factor** = ϕ^{-1} (dimensionless)

- Thermal Noise Reduction:
 1. **Lower Temperature**
 2. **Larger Test Mass**
 3. **Increase Q factor** to shift noise above the signal band
- The **mechanical Q-factor** varies with **Temperature**.
- Some materials show a **peak in Q-factor** at certain low temperatures due to changes in **atomic lattice vibrations**.

1. To reach a lower temperature

Radiative Cooling:

- Interlacing fins to increase the radiative heat exchange area (80m² for E-TEST, ~500m² for ET).
- Thermo-mech. topology optimisation of fin geometry with radiation
- Emissivity enhancement at low temperature (coating)



1. To reach a lower temperature

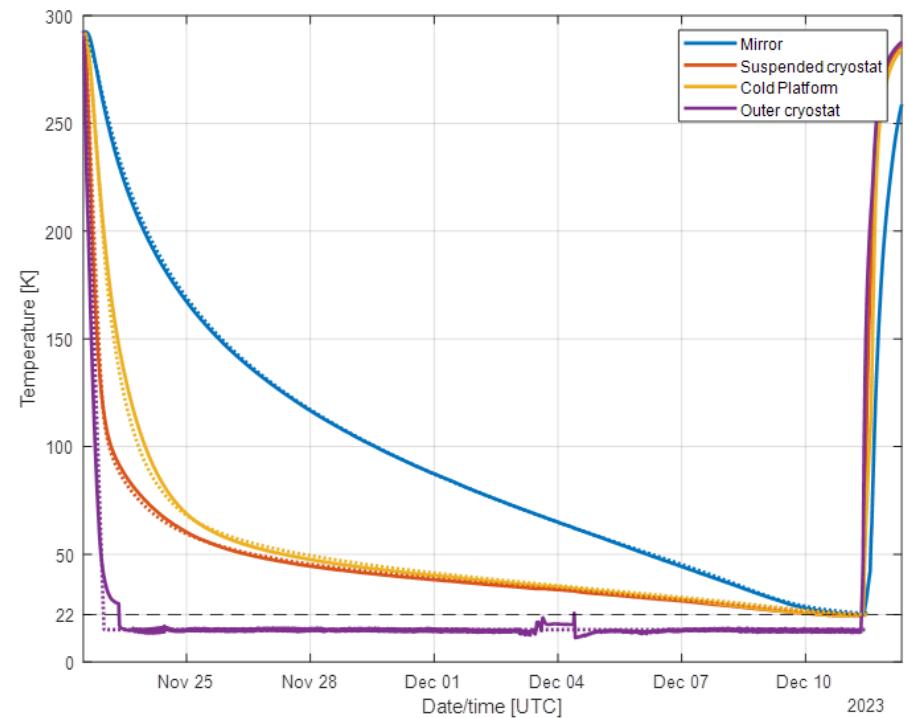
Prototype assembly completed
Nov 2023



First Run (Vacuum)



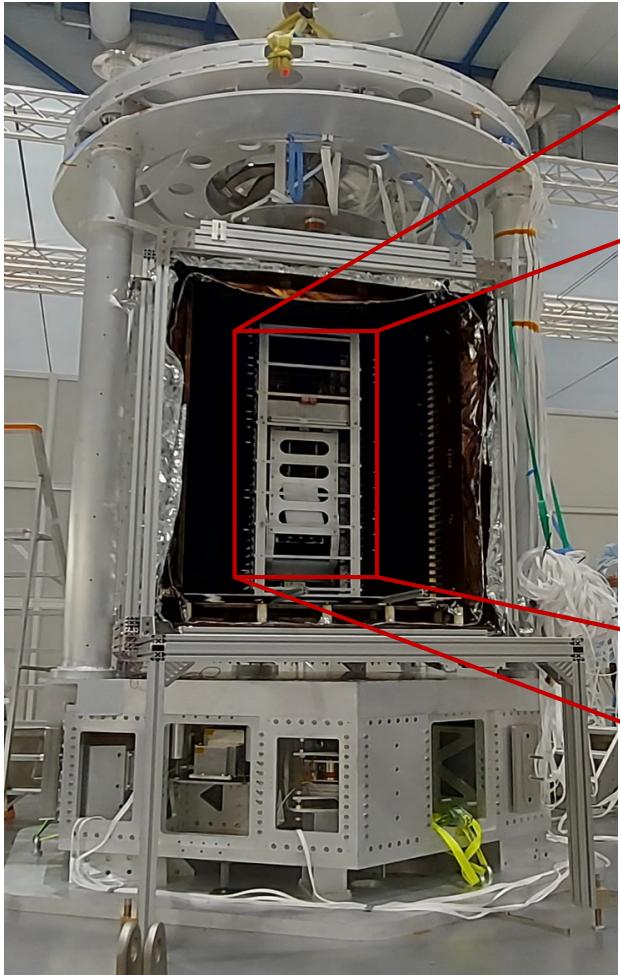
1st run at CSL 2023
22K achieved in 18days !



Ref: Jacques Lionel et al.

Note: Dummy Test Mass (Aluminium) was used.

2. TEST MASS (First Run:2023)



2023: 1st Run: Dummy Test mass

- CuCrZr Suspensions
- Aluminium ears attached to TM
- Black painted finish

2. TEST MASS (Second Run:2025)



- Monocrystalline (Silicon)
Magnetic Czochralski Process
- Diameter: 45 cm
- Mass: 90 kg



Additionally,

1. Mid-tier mass, Cylindrical, $\varnothing 4.27$ cm, 3 cm, ~ 100 g
2. Intermediate mass, Cylindrical, $\varnothing 10$ cm, 10 cm, ~ 1.83 kg

Meeting specific minimum Requirements such as
Roughness <2 nm RMS, Flatness $\lambda/4$,
Parallelism <30 μ rad, ROC ∞ (Flat) etc.

Ref: SINGLE CRYSTAL Silicon database(ET_docs)

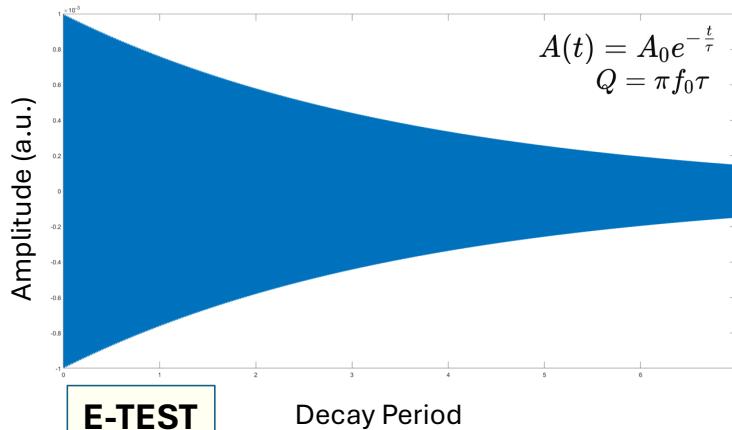
- Diameter: 45 cm
- Thickness ~ 17 cm



3. Mechanical Loss Measurement

Traditional Q- Measurement Method

Monocrystalline Si @ cryo \rightarrow ultra-high Q, long ring-down!



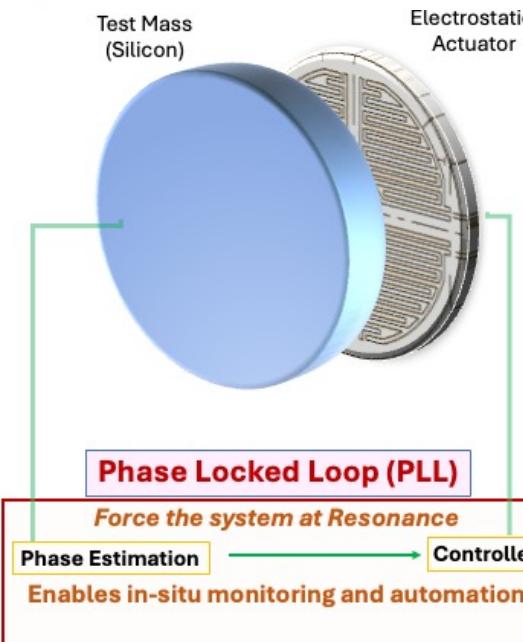
High Q-Factor Silicon Resonator Setup

- Non-Contact Cool Down and **Actuation** (@resonant frequency) of the Test Mass (Si)
- **Minimal damping, Lower Thermal Noise!!**

Ref: PLL: [Nic Smith et al.](#), ESD: [John Miller Thesis](#), LIGO-T1700446, Challenges : LIGO-T1400226/010

Why PLL?

- Ring-down too slow for **Silicon**
- Faster, **Real-time tracking of Resonance, Continuous measurement**, no waiting for decay.



Challenges: Non-Contact Method

- Development of **ESD** approach and analysis of **Eddy current** generation, unpredictable **electric fringe interactions** due to **semiconducting** properties
- Integration with Phase-Locked Loop (**PLL**)
- **Compatibility** with cryogenic operation

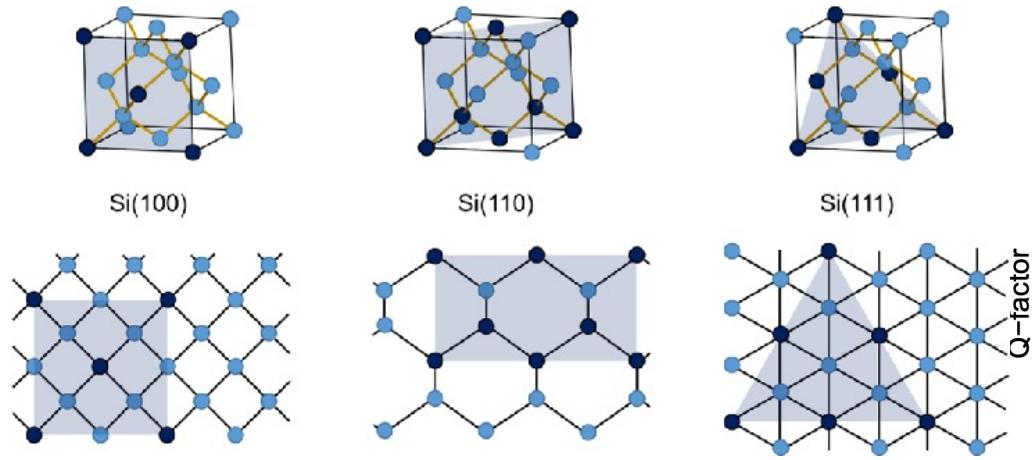
Q v/s Temp relationship !!

@François Winand
francois.winand@uliege.be

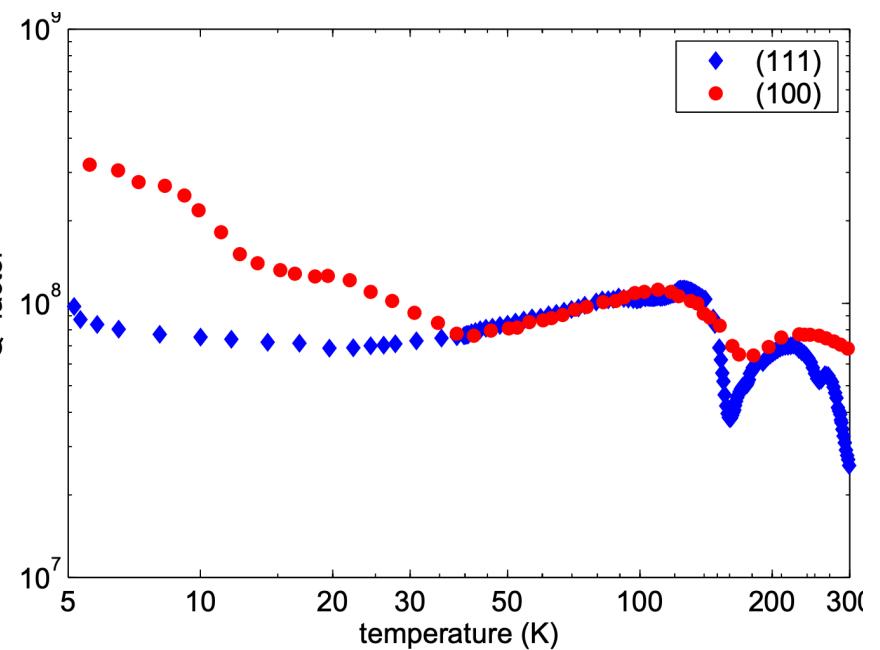
Mechanical Loss Measurement

As **Q vs T plot** reveals mechanical behaviour of Si Test Mass at **negative CTE (~120K)!!**

- $<40\text{ K: Si}(100) > \text{Si}(111) \text{ Q}$
- Lower phonon scattering
- Reduced dislocation mobility
- Reduced internal friction



Dependency on Crystal orientations



Development of Actuator

Non-contact Method

aLIGO
For 40 kg mass
Max force: 400 μ N at 950 V

To achieve the same displacement
For 100 kg Test mass,
1000 μ N Force required!!

Explored two candidates (for E-TEST)

1. Photon Actuators ($P \sim 150\text{ kW}$)
2. Electrostatic Actuator ($V \sim 1\text{ kV}$)

Resulting Force

$$F_{\text{ESD}} = \alpha(\Delta V)^2,$$

a : ESD actuation coefficient, depends on the separation, material properties, and ESD geometry.

$$a = 2.95 \times 10^{-10} \text{ N/V}^2$$

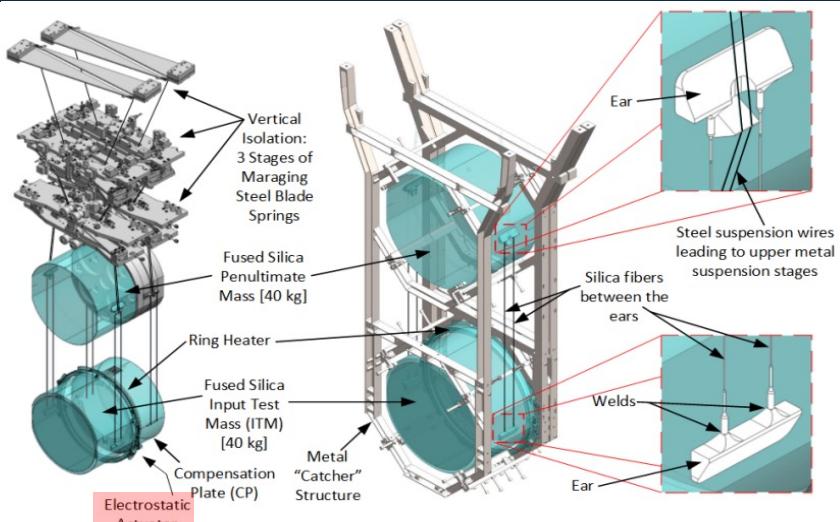
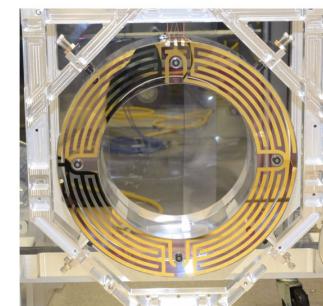
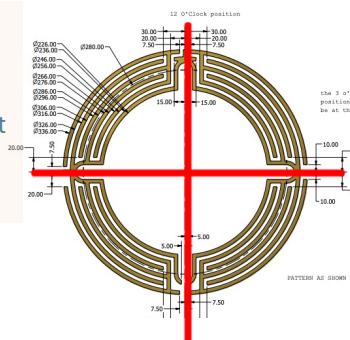


Figure 8 Quadruple pendulum suspension for the Input Test Mass (ITM) optic.

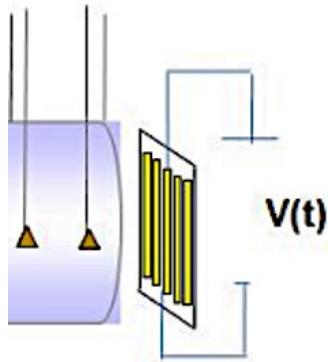
Four Quadrants (DC + AC)

DC bias: creating a static charge environment
AC modulation: oscillating the force



Electrostatic Actuator

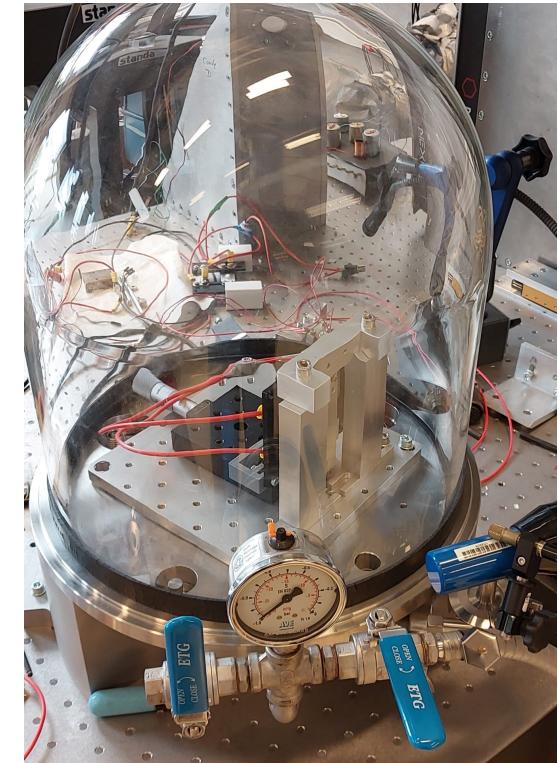
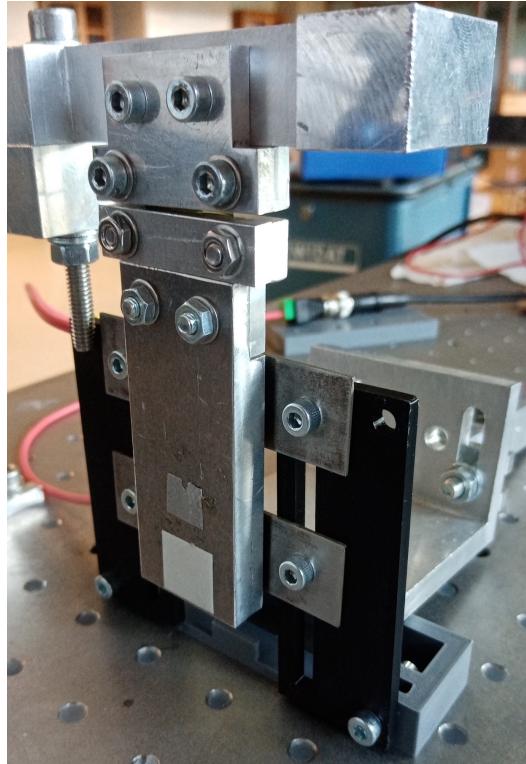
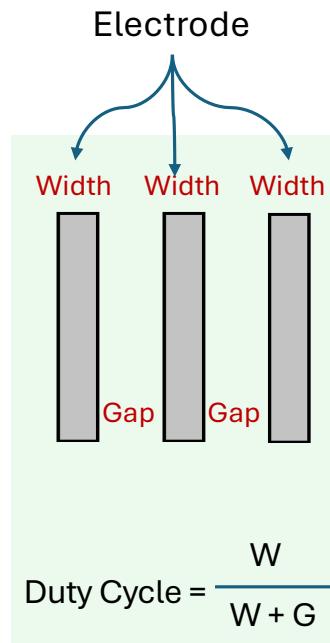
Preliminary Findings



Force depends on:

- Voltage (V)
- Gap distances
- Area of interaction (Fringes)

$$F = \frac{1}{2} \epsilon A E^2, \text{ and } E = \frac{V}{d}$$

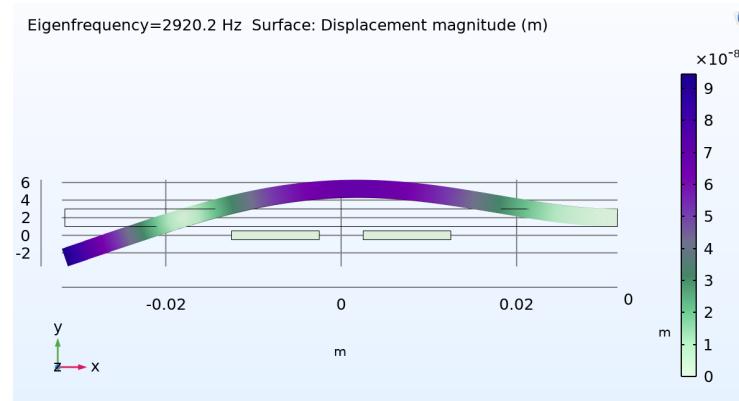
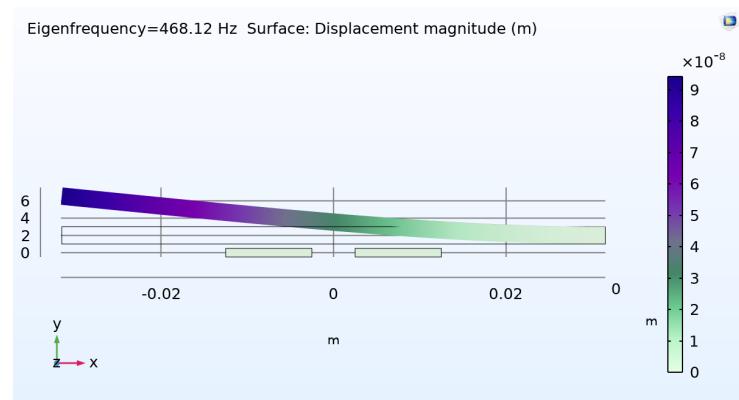
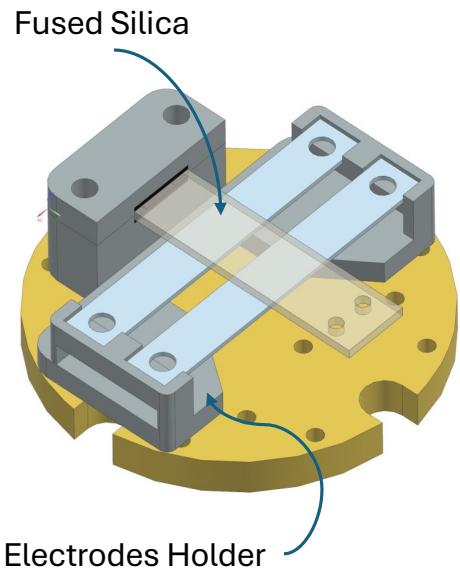


Observations so far:

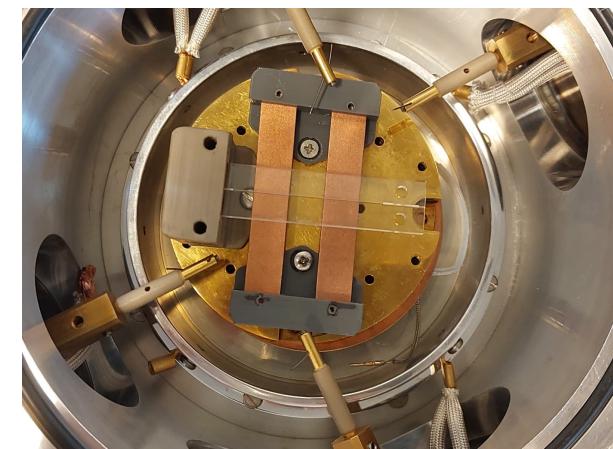
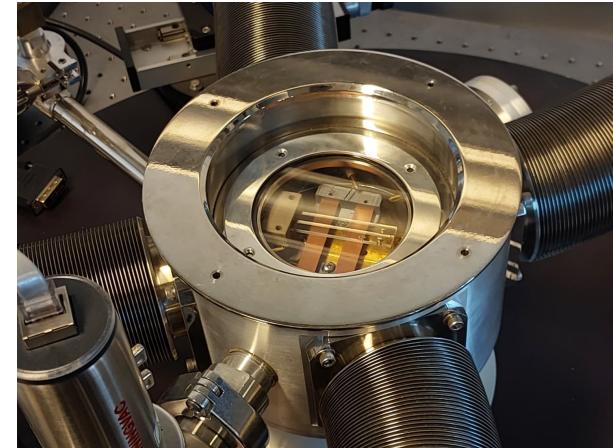
- DC bias with AC bias produces better results.
- Duty Cycle ~ 50% works better etc.

Electrostatic Actuator

In Progress



Multiphysics Simulation (COMSOL)



Experiment

Temperature Measurement (Non- contact Method)

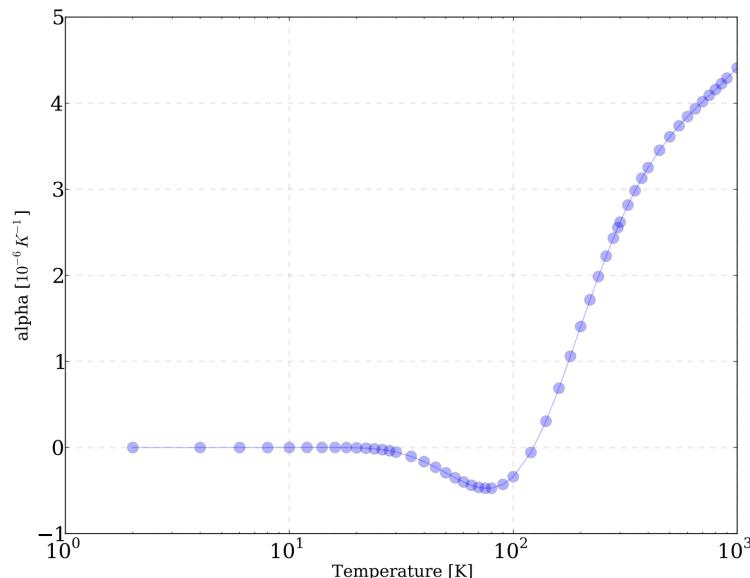
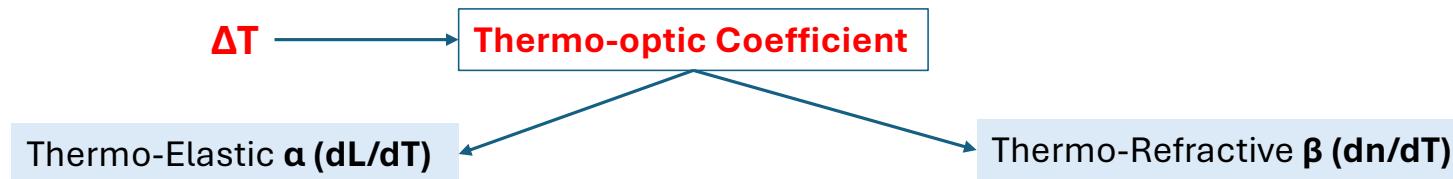


Fig: CTE of Si as function of T

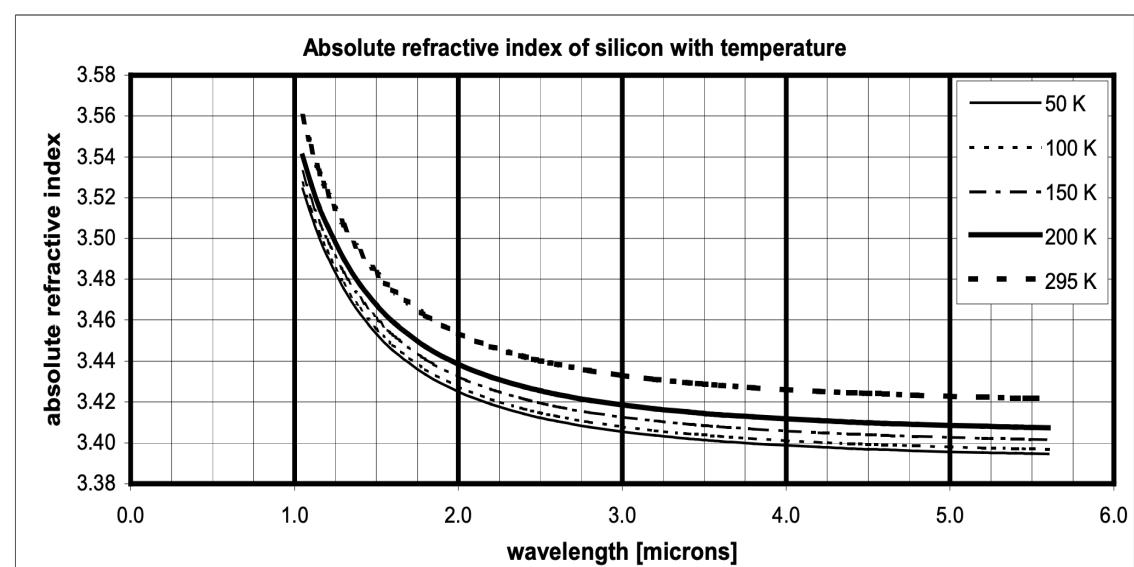


Fig: Measured absolute refractive Index of Silicon as a function of wavelength for selected Temperature

Temperature Measurement (Non- contact Method)

Thermo-refractive Coefficient (β)

i. Silicon (monocrystalline Structure, Semiconductor)

Refractive Index \longrightarrow Electronic structure and polarizability.
High (n) in IR

ii. Heat Generation

Scattering due to +
Free carriers
 (unbound electrons and holes)

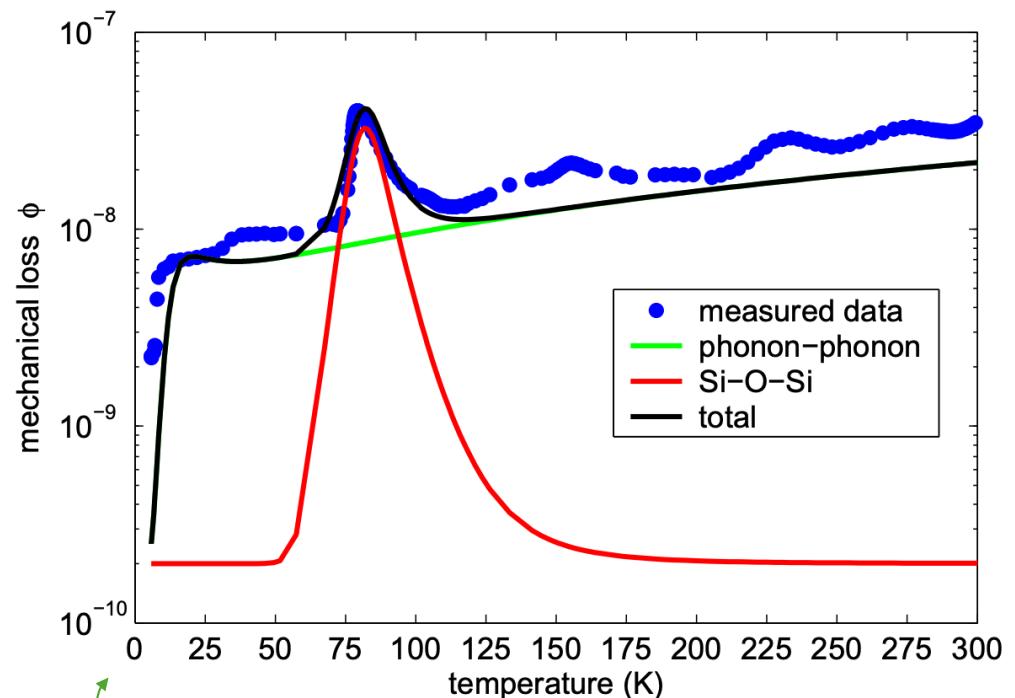
Laser light
 Absorption

1. Inter-band absorption
2. Two-photon absorption
- 3. Free carrier absorption**
 (@NIR/IR wavelength)

$$\alpha_{FC} = \frac{e^2 \lambda^2}{4\pi \epsilon_0 n c^3} \frac{n_c}{m_*^2 \mu}$$

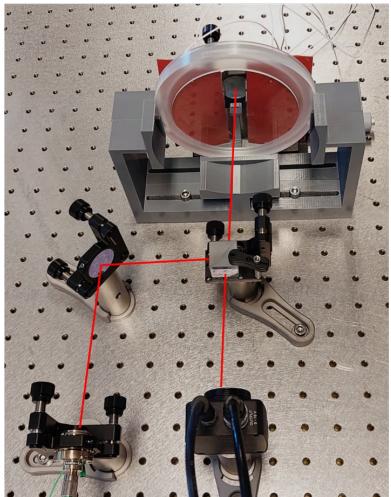
α_{FC} : Free carrier absorption coefficient
 e : Elementary charge
 λ : Wavelength of Light
 ϵ_0 : Vacuum permittivity
 n : Refractive index
 c : Speed of light in vacuum
 n_c : Free carrier concentration
 m_* : Effective mass of the carrier
 μ : Carrier mobility

Increases the phonon interactions (local heating)

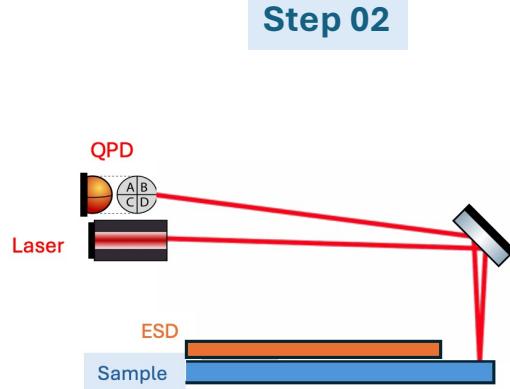


Experimental Framework: Temperature Measurement

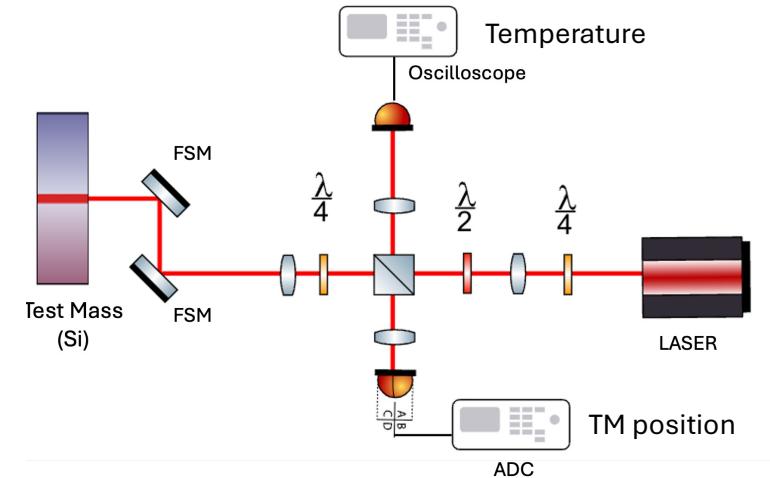
Step 01



Step 02



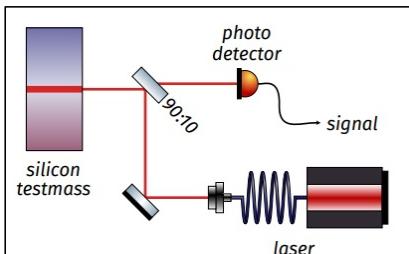
Step 03



@Janis Wöhler

Considerations:

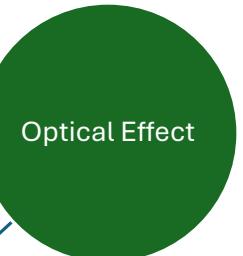
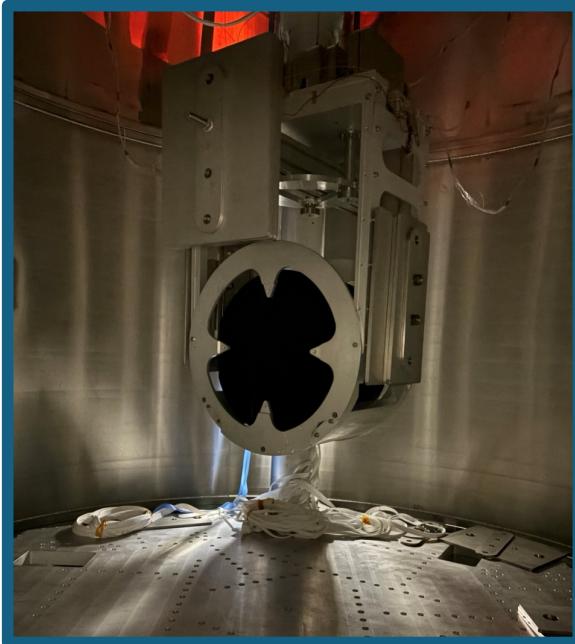
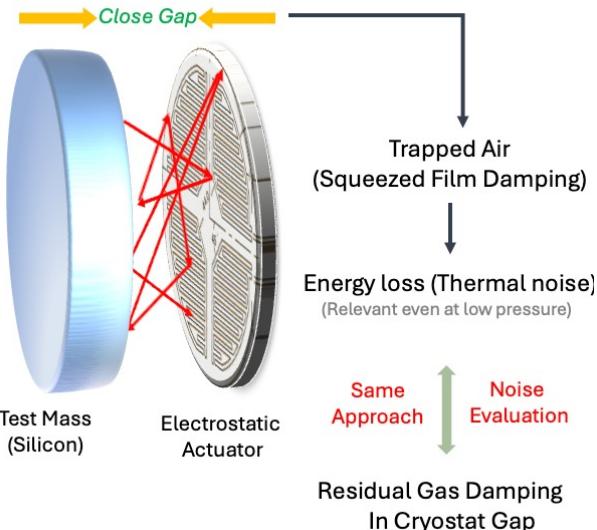
- Effects of ground motion
- LASER (Wavelengths: 1550 nm vs. 2000 nm)
- Scalability



$OPL \rightarrow \Delta T \rightarrow \Delta L \& \Delta n \rightarrow \text{Fringe shift}$



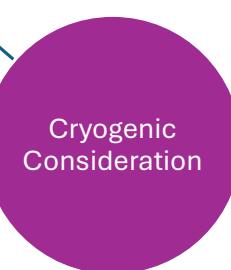
Supplementary Studies



- Laser Absorption Spectra
- Free Carrier Absorption
- Birefringence in Test Mass
- Parametric Instabilities



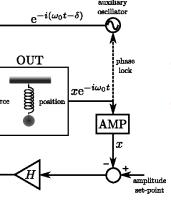
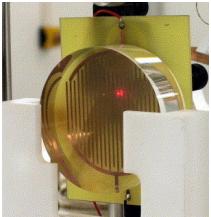
- Charge Induction and Interaction on surfaces
- Reliability of ESD
- Thermal Gradients in the Material
- Effects of Impurities & Orientation on internal Friction



- Ice formation during cooldown
- Impact on optical and mechanical performance
- Residual air squeezed damping

Summary

Quality Factor (Q) Measurement



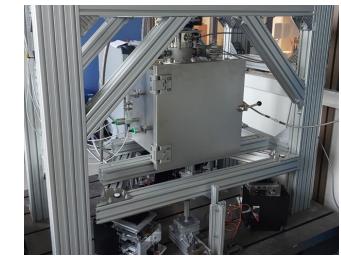
Study AC, DC, and AC+DC Current effects

ESD designs: Duty Cycle impact on Fringe Generation

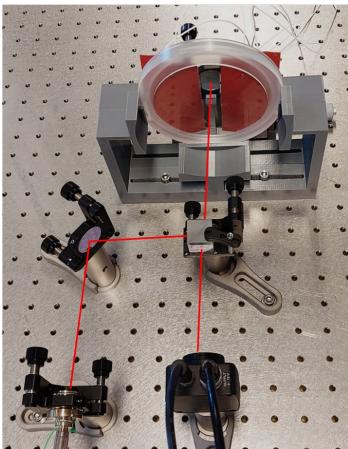
Fused silica & Silicon samples

Apply Phase-Locked Loop

Cryogenic testing



Temperature Measurement



Ongoing

Fringes $\rightarrow \alpha$ & β (predict thermo-optic coefficients due to Δ OPL)

Laser stabilization, Wavelength absorption & Thermal Gradient (1550 nm vs 2000 nm)

Final Optical Setup

Integration

Real-time Q vs T monitoring

E-TEST
(2026)

E-Test: Experimental facility RoadMap

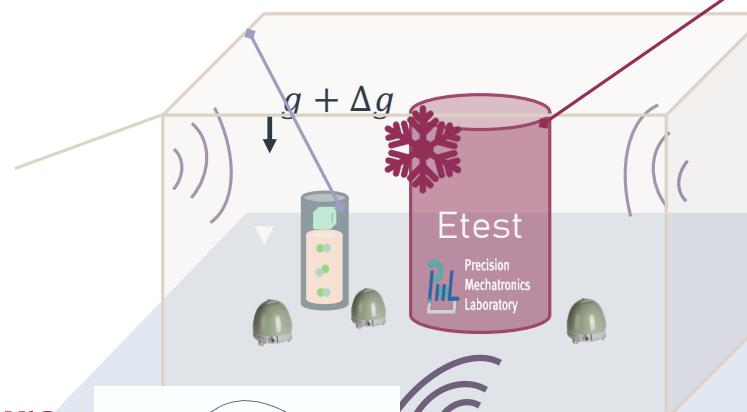
2023, prototype assembled and tested:

- Suspension for 100 kg
- Instrumentation developed
- Radiative cooling validated

Si suspension + surface treatment
Characterisation
(traction tests + inspection)
ET Fiber project



2025: installation at CSL



2026: R&D @ Cryogenic Temperature

- **Active Isolation & control development**
- **Silicon Test Mass Installation & ETFIBER**
- **Inertial sensors development**
- **Newtonian Noise subtraction techniques.**

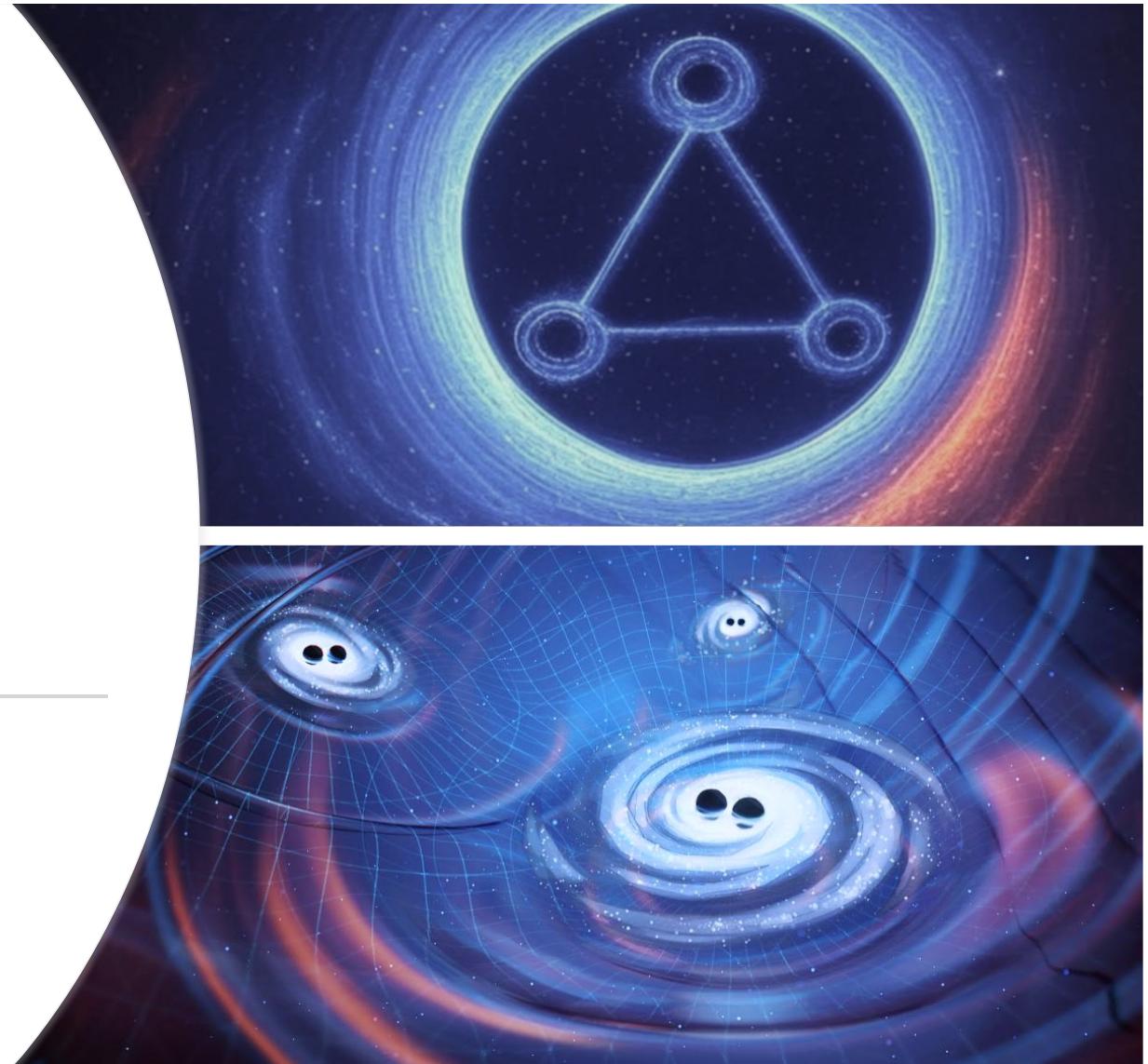


Si Test Mass



Shaker

Thank you!!



Additional

Silicon Mechanical Loss Map

